

PATENT ASSIGNMENT

Electronic Version v1.1
 Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
Solid State Measurements, Inc.	03/04/2013
RECEIVING PARTY DATA	
Name:	Semiconductor Physics Laboratory, Inc.
Street Address:	Prielle Kornelia u. 2.
City:	Budapest
State/Country:	HUNGARY
Postal Code:	1117
PROPERTY NUMBERS Total: 15	
Property Type	Number
Patent Number:	7285963
Patent Number:	7362108
Patent Number:	7282941
Patent Number:	6597185
Patent Number:	7102363
Patent Number:	6657454
Patent Number:	6492827
Patent Number:	7063992
Patent Number:	6991948
Patent Number:	6632691
Patent Number:	6052653
Patent Number:	6741093
Patent Number:	6150832
Patent Number:	6842029
Patent Number:	6856140

OP \$600.00 7285963

CORRESPONDENCE DATA

Fax Number: 4129455933

Correspondence will be sent via US Mail when the fax attempt is unsuccessful.

Phone: 4124718815

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Address Line 2: Suite 1200

Address Line 4: Pittsburgh, PENNSYLVANIA 15222

ATTORNEY DOCKET NUMBER:

1880-111151

NAME OF SUBMITTER:

William H. Logsdon

Signature:

/William H. Logsdon/

Date:

04/08/2013

Total Attachments: 5

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**RECORDATION FORM COVER SHEET
PATENTS ONLY**

To the Director of the U.S. Patent and Trademark Office: Please record the attached documents or the new address(es) below.

1. Name of conveying party(ies)

Solid State Measurements, Inc.

Additional name(s) of conveying party(ies) attached? ☐ Yes ☒ No

3. Nature of conveyance/Execution Date(s):

Execution Date(s) March 4, 2013

- ☒ Assignment ☐ Merger
☐ Security Agreement ☐ Change of Name
☐ Joint Research Agreement
☐ Government Interest Assignment
☐ Executive Order 9424, Confirmatory License
☐ Other _____

2. Name and address of receiving party(ies)

Name: Semiconductor Physics Laboratory, Inc.

Internal Address: _____

Street Address: Prielle Kornélia u. 2.

City: Budapest

State: _____

Country: Hungary Zip: 1117

Additional name(s) & address(es) attached? ☐ Yes ☒ No

4. Application or patent number(s):

☐ This document is being filed together with a new application.

A. Patent Application No.(s)

B. Patent No.(s)

7,285,963	7,362,108	7,282,941
6,597,185	7,102,363	6,657,454
6,492,827	7,063,992	6,991,948

Additional numbers attached? ☒ Yes ☐ No

5. Name and address to whom correspondence concerning document should be mailed:

Name: William H. Logsdon

Internal Address: The Webb Law Firm

Street Address: One Gateway Center
420 Ft. Duquesne Blvd., Ste 1200

City: Pittsburgh

State: PA Zip: 15222

Phone Number: 412-471-8815

Fax Number: 412-945-5933

Email Address: assignments@webblaw.com

6. Total number of applications and patents involved: 15

7. Total fee (37 CFR 1.21(h) & 3.41) \$ 600

- ☒ Authorized to be charged by credit card
☐ Authorized to be charged to deposit account
☐ Enclosed
☐ None required (government interest not affecting title)

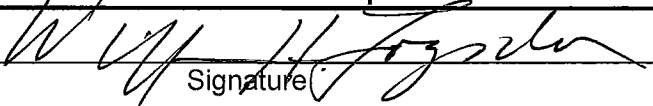
8. Payment Information

a. Credit Card Last 4 Numbers 4775
Expiration Date 05/2015

b. Deposit Account Number 23-0650

Authorized User Name William H. Logsdon

9. Signature:


Signature

April 8, 2013

Date

William H. Logsdon

Name of Person Signing

Total number of pages including cover sheet, attachments, and documents:

2

Documents to be recorded (including cover sheet) should be faxed to (571) 273-0140, or mailed to:
Mail Stop Assignment Recordation Services, Director of the USPTO, P.O.Box 1450, Alexandria, V.A. 22313-1450

Additional Patent Nos.

6,632,691

6,052,653

6,741,093

6,150,832

6,842,029

6,856,140

ÁTRUHÁZÁSI NYILATKOZAT

DECLARATION OF ASSIGNMENT

Alulírott / The undersigned

Solid State Measurements, Inc.

110 Technology Drive

Pittsburgh, PA 15275

United States of America

(továbbiakban: "Átruházó") ezennel kijelenti, hogy az alábbi, *A függelékben* felsorolt Amerikai Egyesült Államokban engedélyezett érvényes szabadalmakat, valamint *B függelékben* felsorolt külföldi szabadalmakat/szabadalmi bejelentéseket minden azokra vonatkozó joggal és kötelezettséggel együtt a /

(hereinafter "Assignor") hereby declares to assign and transfer the following valid U.S. Patents listed in *Exhibit A* and the following foreign Patents/Patent Applications listed in *Exhibit B* with all rights, title and interest therein to

Semiconductor Physics Laboratory, Inc.

Prielle Kornélia u. 2.

1117 Budapest

Hungary

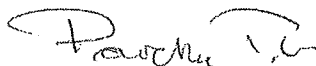
részére (továbbiakban "Engedményezett") engedményezi és átruházza. /

(hereinafter "Assignee").

Kelt: / Date:

04 March 2013

Solid State Measurements, Inc.



(Tibor PAVELKA, elnök vezérigazgató / CEO)

Átruházó / Assignor

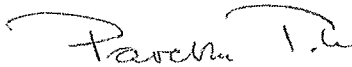
Alulírott Engedményezett a fenti engedményezést és átruházást elfogadja.

We the undersigned Assignee declare to accept the preceding assignment and transfer.

Kelt: / Date:

04 March 2013

Semiconductor Physics Laboratory, Inc.



(Tibor PAVELKA, elnök vezérigazgató / CEO)

Engedményezett / Assignee

SEMILAB
Semiconductor Physics
Laboratory Co. Ltd.

PATENT

REEL: 030172 FRAME: 0096

Exhibit A

Patent No.	Title	Date Filed	Date Issued
7,285,963	"Method and System for Measurement of Dielectric Constant of Thin Films Using a Near Field Microwave Probe"	4/8/2005	10/23/2007
7,362,108	"Method and System for Measurement of Sidewall Damage in Etched Dielectric Structures Using a Near Field Microwave Probe"	10/14/2005	4/22/2008
7,282,941	"Method of Measuring Semiconductor Wafers with an Oxide Enhanced Probe"	4/5/2005	10/16/2007
6,597,185	"Apparatus for Localized Measurements of Complex Permittivity of a Material"	9/20/2000	7/22/2003
7,102,363	"Method and System for Non-Contact Measurement of Microwave Capacitance of Miniature Structures of Integrated Circuits"	5/26/2005	9/5/2006
6,657,454	"High Speed Threshold Voltage and Average Surface Doping Measurements"	3/15/2002	12/2/2003
6,492,827	"Non-Invasive Electrical Measurement of Semiconductor Wafers"	10/19/2000	12/10/2002
7,063,992	"Semiconductor Substrate Preparation Using High Temperature Convection Heating"	8/8/2003	6/20/2006
6,991,948	"Method of Electrical Characterization of a Silicon-on-Insulator (SOI) Wafer"	11/5/2003	1/31/2006
6,632,691	"Apparatus and Method for Determining Doping Concentration of a Semiconductor Wafer"	4/11/2002	10/14/2003
6,052,653	"Spreading Resistance Profiling System"	7/11/1997	4/18/2000
6,741,093	"Method of Detecting Carrier Dose of a Semiconductor Wafer"	3/18/2002	5/25/2004
6,150,832	"Noncontact Capacitance Measuring Device"	3/19/1999	11/21/2000
6,842,029	"Non-Invasive Electrical Measurement of Semiconductor Wafers"	4/11/2002	01/11/2005
6,856,140	"System and Method for Quantitative Measurements of a Material's Complex Permittivity with the Use of Near-Field Microwave Probes"	4/14/2003	02/15/2005

Exhibit B

Title	Application/Patent No.	Date filed	Date issued
"Method and Apparatus for Determining the Dielectric Constant of a Low Permittivity Dielectric on a Semiconductor Wafer"	JP4685434	12/27/2004	02/18/2011
"Apparatus for Localized Measurements of Complex Permittivity of a Material"	JP 283433/2001	09/18/2001	to be granted
"Spreading Resistance Profiling System"	EP-1,000,363	07/10/1998	08/30/2006
"Non-Invasive Measurement of Electrical Properties of a Dielectric Layer in a Semiconductor Wafer"	EP-1,256,006	10/19/2000	07/19/2006
"Sample chuck with compound construction"	EP-1,276,145	07/10/2002	03/21/2007
"Method and apparatus for testing semiconductor wafers"	EP-1,286,389	08/22/2002	10/04/2006
"Method and apparatus for measuring charge carrier lifetime of a semiconductor wafer"	EP-1,413,892	10/22/2003	05/25/2008
"Conductance-voltage (GV) based method for determining leakage current in dielectrics"	EP-1,530,053	11/03/2004	02/28/2007
"Method of Measuring Semiconductor Wafers With an Oxide Enhanced Probe"	EP-1,710,594	04/05/2006	07/16/2008
"Method of Measuring Semiconductor Wafers with an Oxide Enhanced Probe"	JP 129571/2006	04/05/2006	pending (?)
"Method of Electrical Characterization of a Silicon-on-Insulator (SOI) Wafer"	TW93123849	08/09/2004	pending
"Work function controlled probe for measuring properties of a semiconductor wafer and method of use thereof"	TW94115310	05/05/2011	to be granted

Respective national patents obtained in member states of the European Patent Convention via national validation of the above-listed EP patents

Title	Application No.	Date filed	Date issued
"Spreading Resistance Profiling System"	PCT/US98/14353	07/10/1998	
"Non-Invasive Measurement of Electrical Properties of a Dielectric Layer in a Semiconductor Wafer"	PCT/US00/41315	10/19/2000	
"Method of Detecting Ion Implant Dose of a Semiconductor Wafer"	PCT/US02/08418	03/19/2002	